Matter No.: 07977-218003 Page 1 of 23

Applicant(s): Shunpei Yamazaki et al.
SEMICONDUCTOR DEVICE AND METHOD OF
MANUFACTURING THE SAME

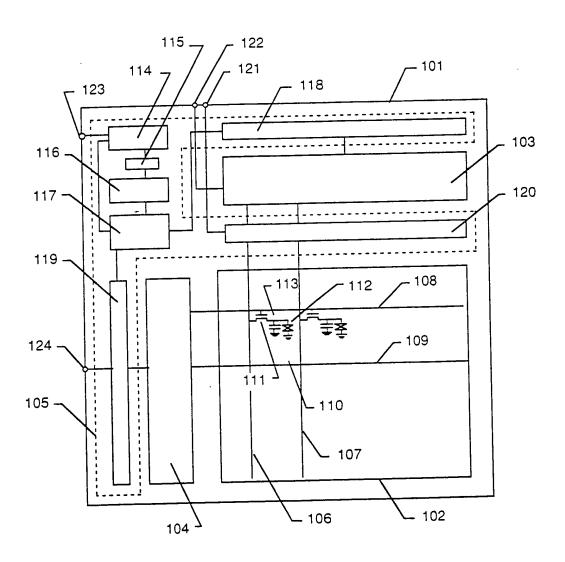
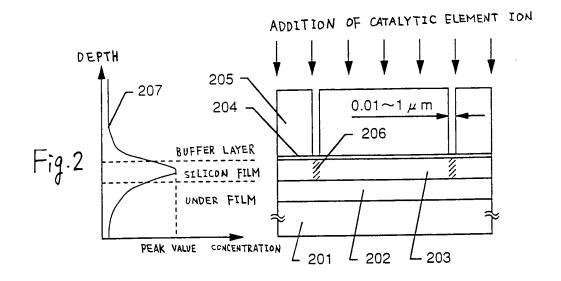
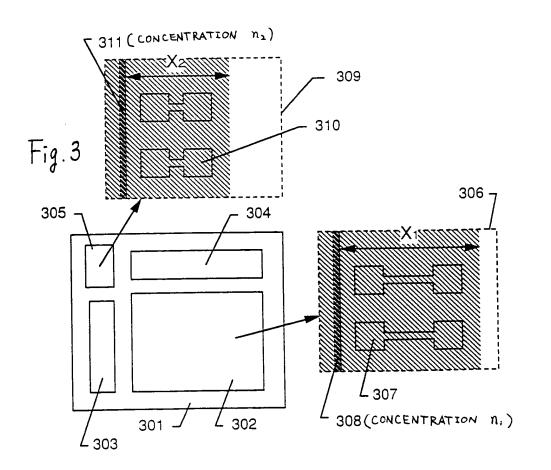


Fig. 1

Matter No.: 07977-218003 Applicant(s): Shunpei Yamazaki et al.

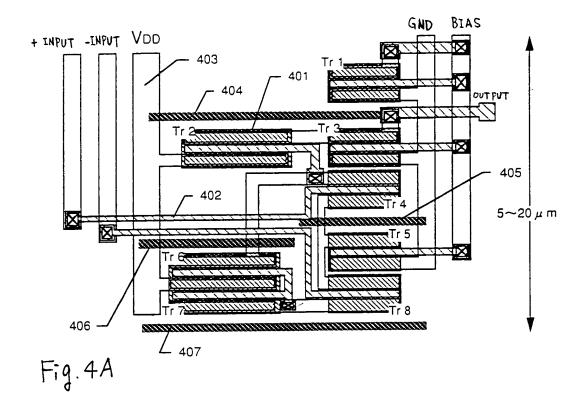
SEMICONDUCTOR DEVICE AND METHOD OF

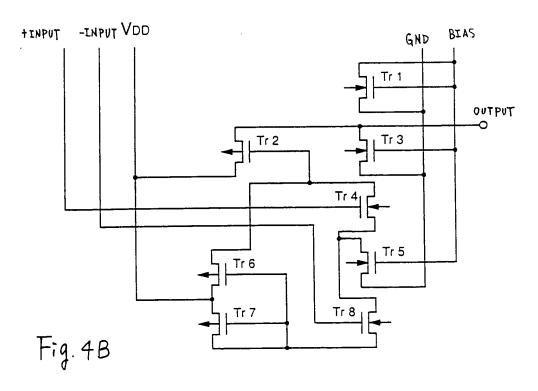




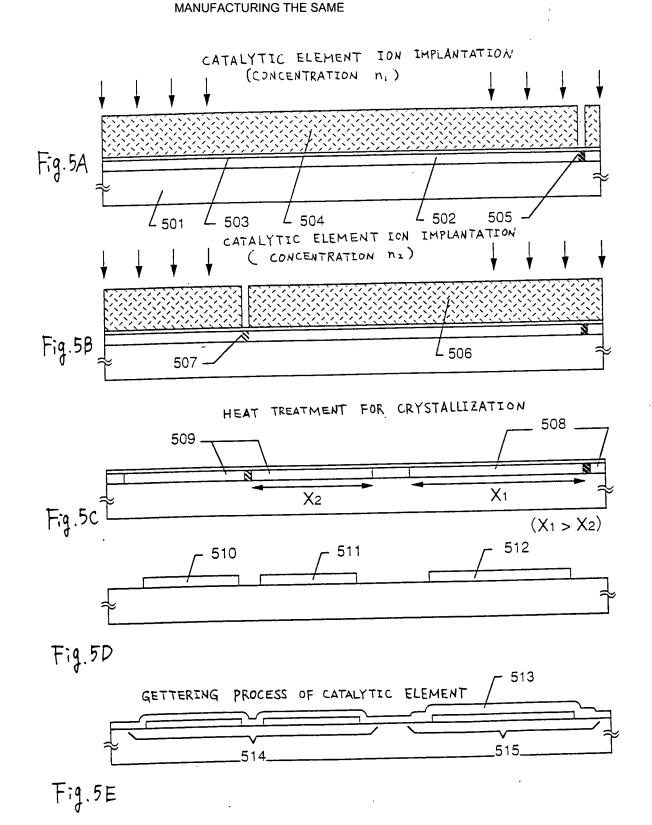
Applicant(s): Shunpei Yamazaki et al.

SEMICONDUCTOR DEVICE AND METHOD OF



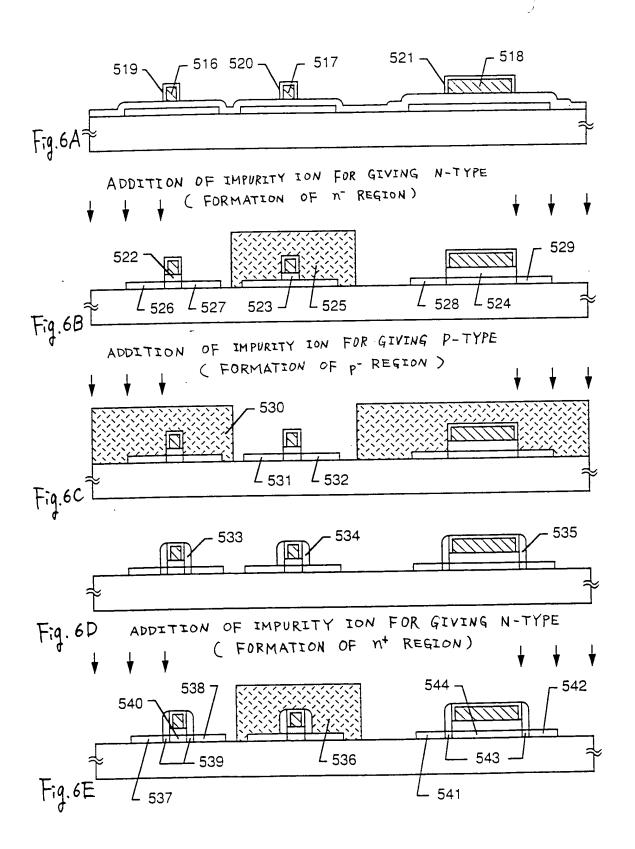


Matter No.: 07977-218003
Applicant(s): Shunpei Yamazaki et al.
SEMICONDUCTOR DEVICE AND METHOD OF



Applicant(s): Shunpei Yamazaki et al.

SEMICONDUCTOR DEVICE AND METHOD OF

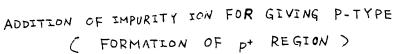


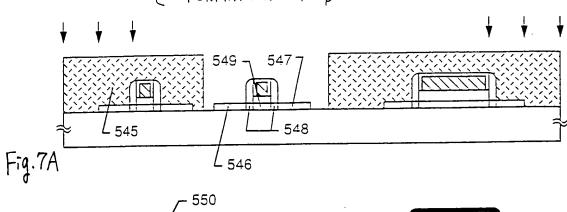
Page 6 of 23

Matter No.: 07977-218003

Applicant(s): Shunpei Yamazaki et al.

SEMICONDUCTOR DEVICE AND METHOD OF





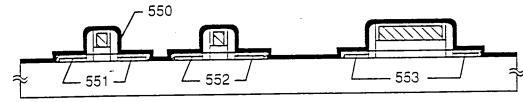


Fig.7B

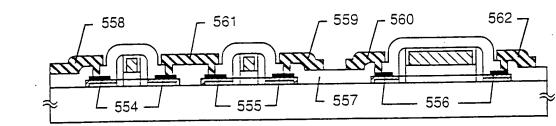
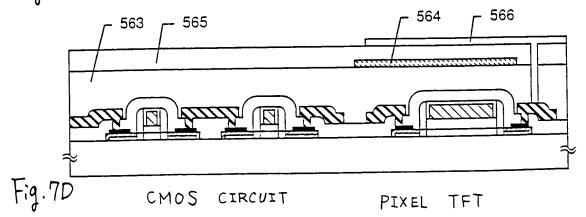


Fig.7C



Page 7 of 23

Matter No.: 07977-218003 Applicant(s): Shunpei Yamazaki et al. SEMICONDUCTOR DEVICE AND METHOD OF MANUFACTURING THE SAME

Fig. 8



Applicant(s): Shunpei Yamazaki et al.

SEMICONDUCTOR DEVICE AND METHOD OF

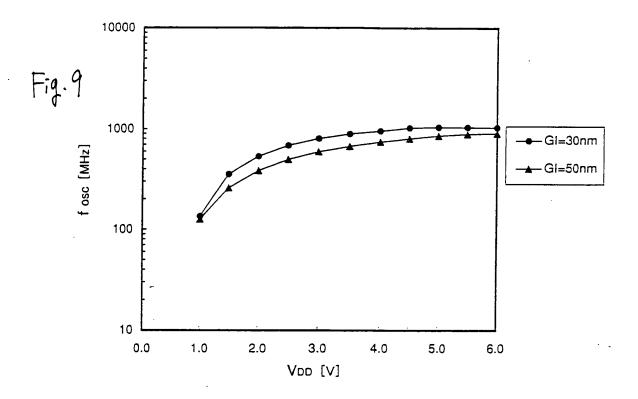
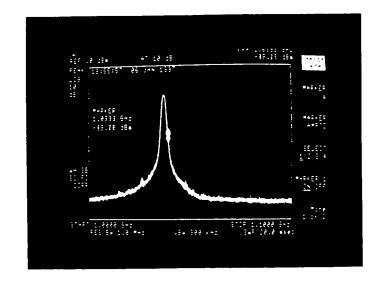


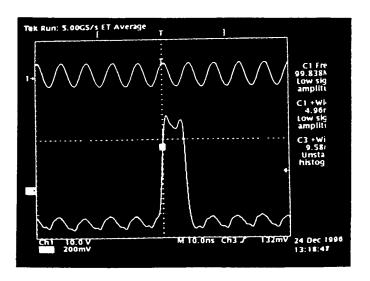
Fig. 10

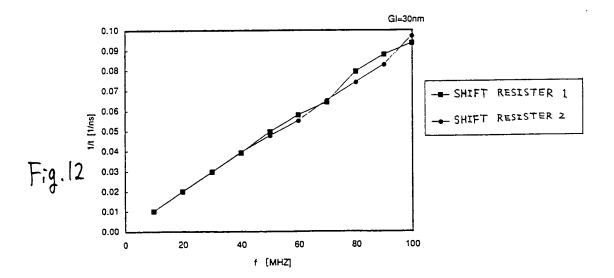


Applicant(s): Shunpei Yamazaki et al.

SEMICONDUCTOR DEVICE AND METHOD OF

Fig. 11





Applicant(s): Shunpei Yamazaki et al.

SEMICONDUCTOR DEVICE AND METHOD OF

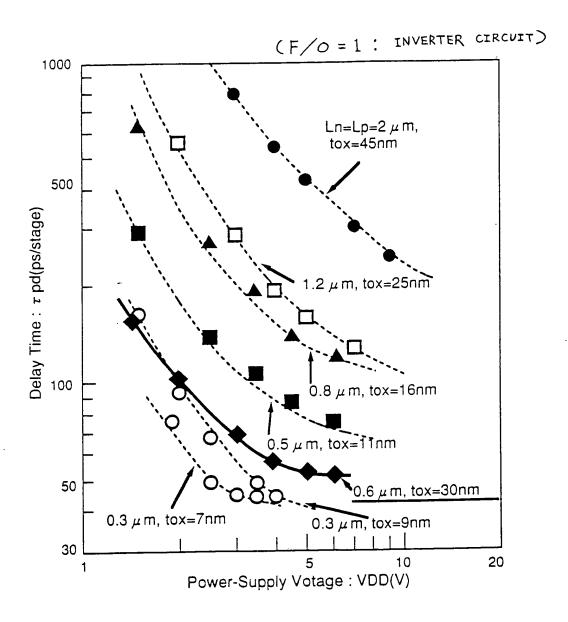


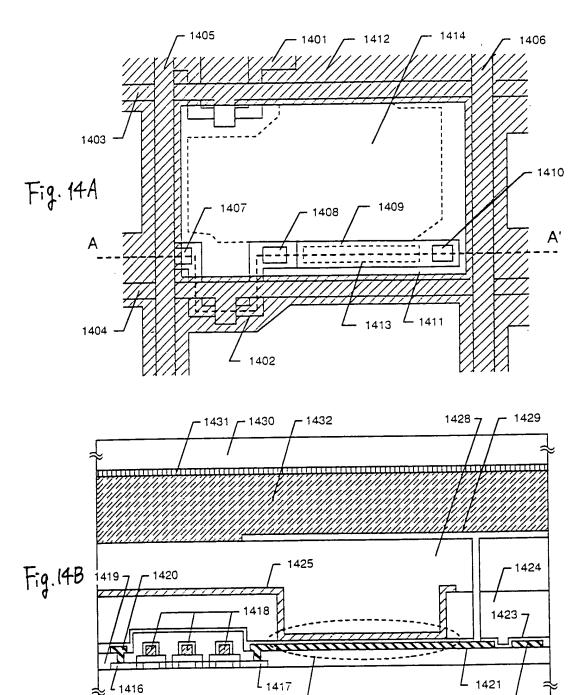
Fig. 13

1422 -

Matter No.: 07977-218003

Applicant(s): Shunpei Yamazaki et al. SEMICONDUCTOR DEVICE AND METHOD OF

MANUFACTURING THE SAME



L 1427

1426

L<sub>1415</sub>

Page 12 of 23

Applicant(s): Shunpei Yamazaki et al. SEMICONDUCTOR DEVICE AND METHOD OF

MANUFACTURING THE SAME

## N-CHANNEL TFT

P-CHANNEL TFT

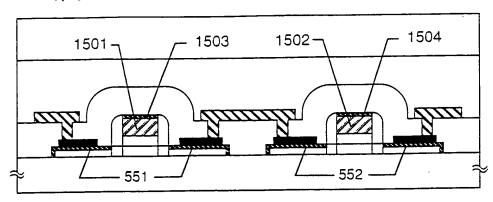


Fig. 15A



P-CHANNEL TFT

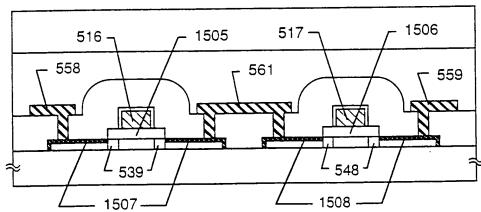
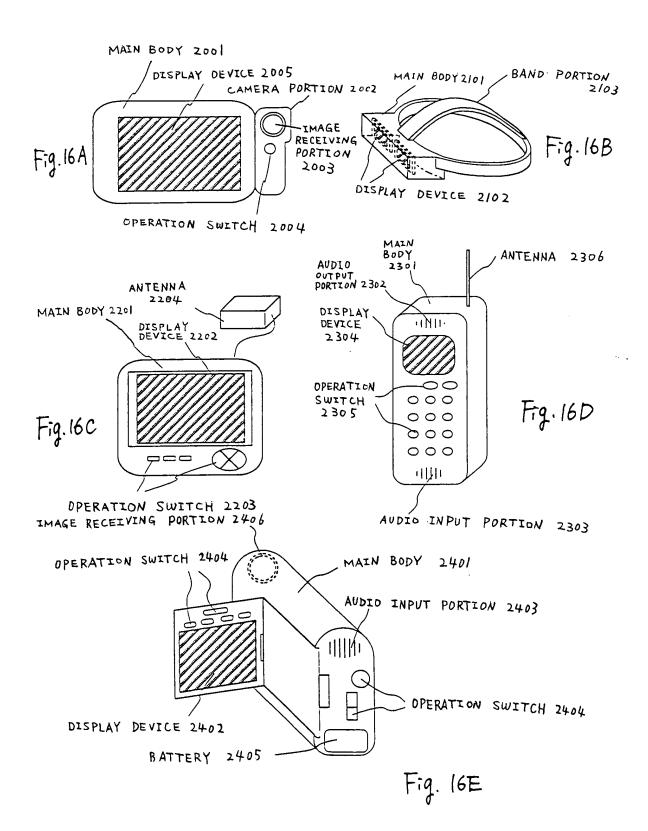


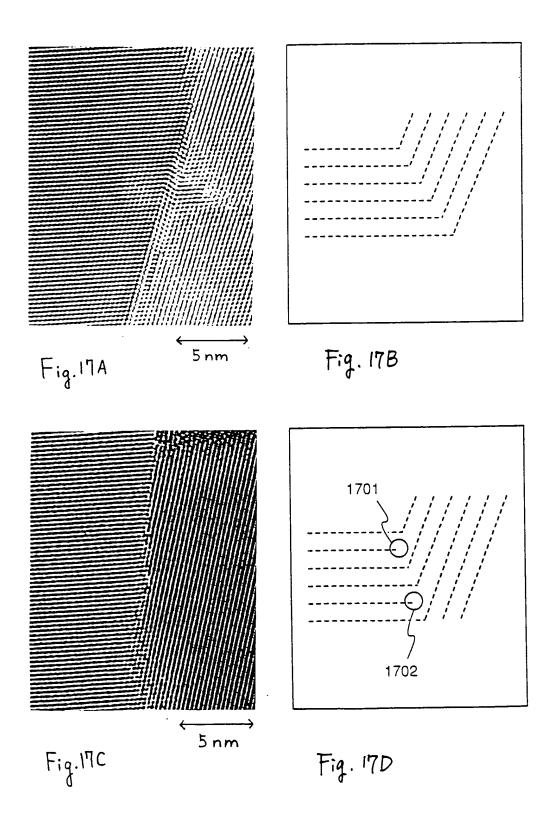
Fig. 15B

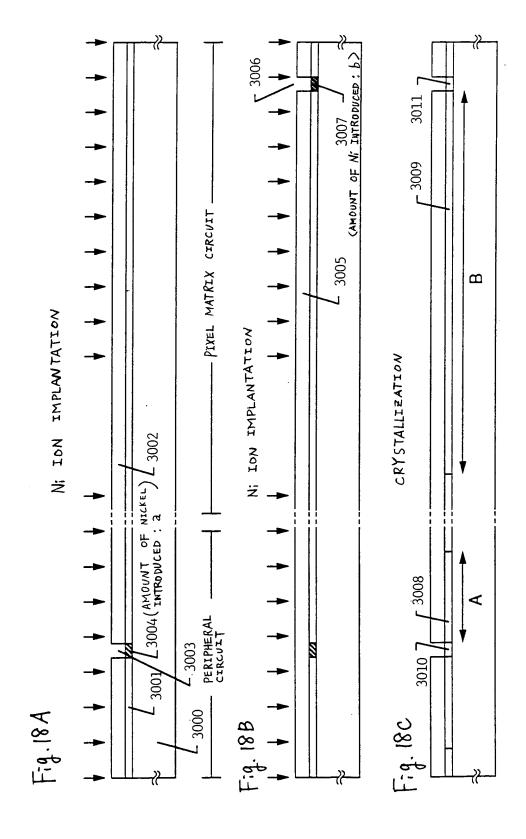
Matter No.: 07977-218003 Page 13 of 23

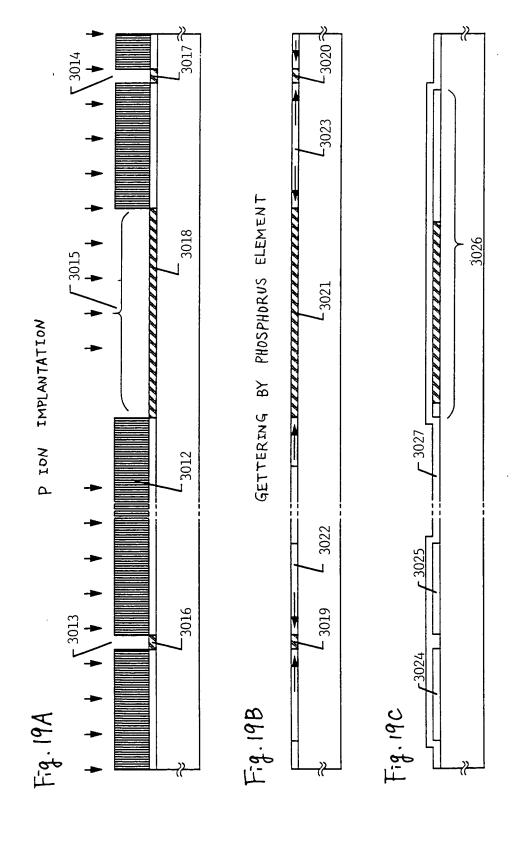
Applicant(s): Shunpei Yamazaki et al.

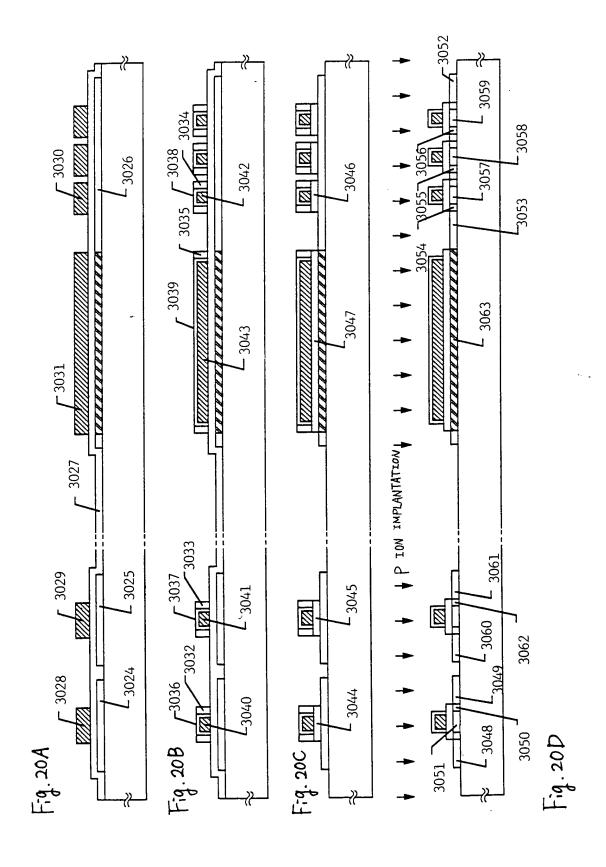
SEMICONDUCTOR DEVICE AND METHOD OF

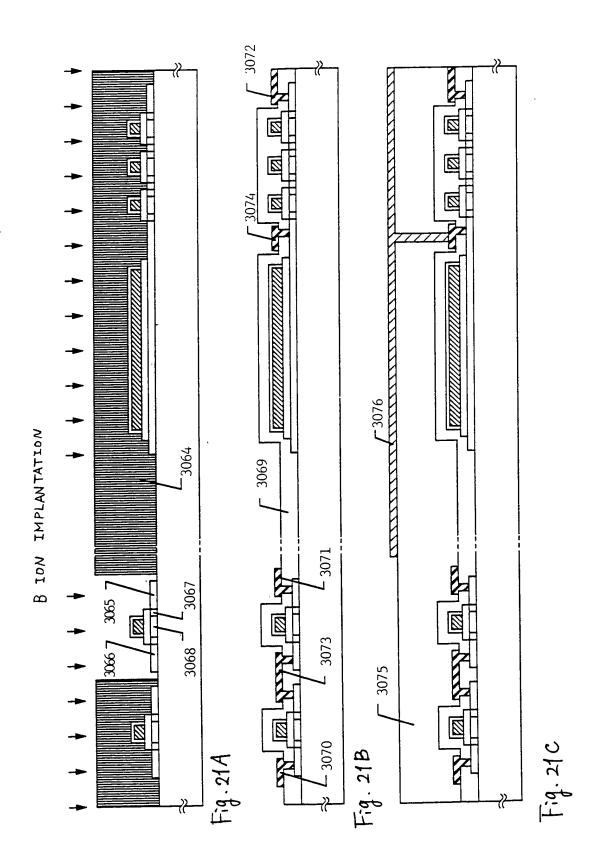


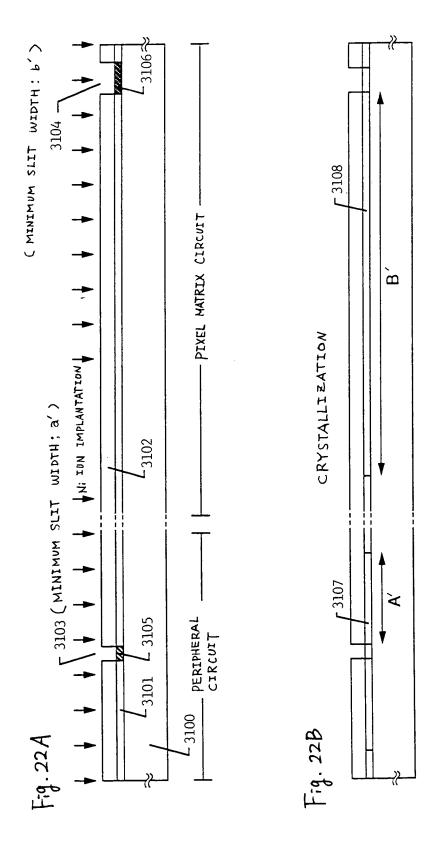










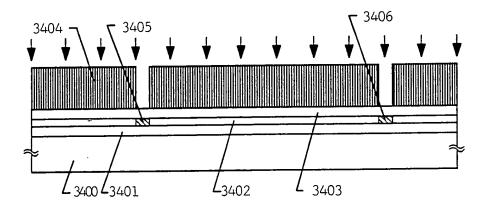


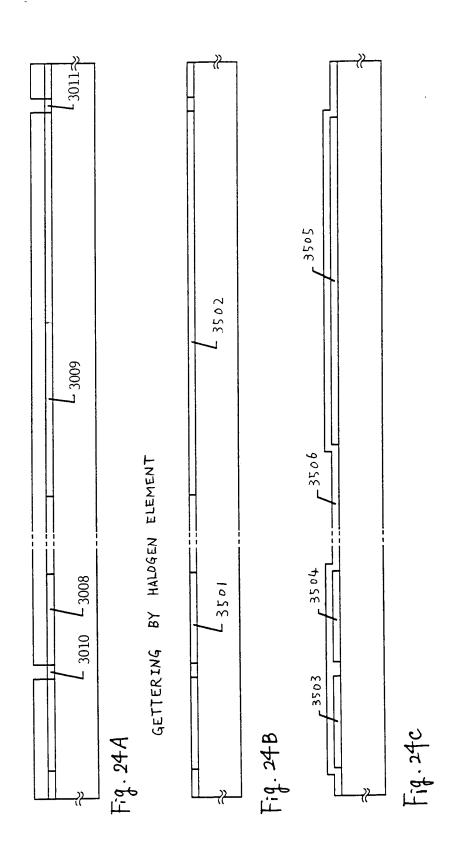
Page 20 of 23

Matter No.: 07977-218003

Applicant(s): Shunpei Yamazaki et al.
SEMICONDUCTOR DEVICE AND METHOD OF
MANUFACTURING THE SAME

## CATALYTIC ELEMENT ION IMPLANTATION





Page 22 of 23

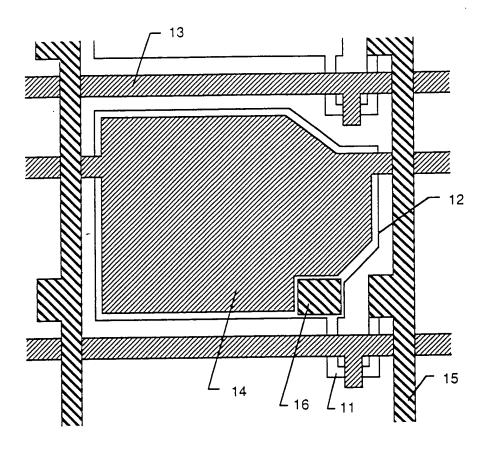


Fig. 25

Applicant(s): Shunpei Yamazaki et al.

SEMICONDUCTOR DEVICE AND METHOD OF

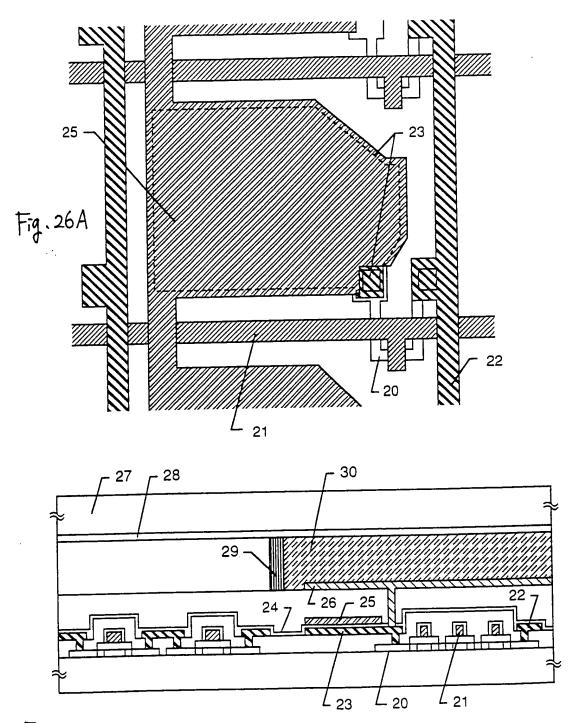


Fig. 26B